

Application No.: 10/763,727
Amendment dated: June 6, 2005
Reply to Non-Compliant Amendment dated: May 5, 2005

AMENDMENTS TO THE ABSTRACT

Please amend the Abstract paragraph as follows:

A system and method for preventing operational and manufacturing imperfections in piezoelectric micro-actuators by physically and electrically isolating conductive layers of the piezoelectric material. At least one layer of electrically-conductive material and at least one layer of electrically-insulative material are applied to an actuator finger. The conductive material and the insulative material are applied one layer upon another in an alternating manner. The layer of insulative material is larger in area than the layer of conductive material. An insulative layer, applied to the actuator finger and sandwiching a conductive layer between the insulative layer and the actuator finger, at least partially encloses and electrically isolates the conductive layer by covering the conductive material on at least three sides.